

**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

**Applicants:** Yong-Pil Han et al.

**Serial No.:** 09/498,303

**Filed:** February 4, 2000

**For:** HF Vapor Phase Wafer Cleaning and Oxide Etching

**Confirmation No.** 8629

**Group Art Unit:** 1763

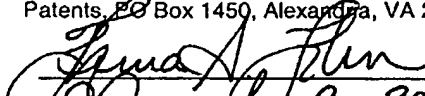
**Examiner:** T. Dang

**COMMISSIONER FOR PATENTS**

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November 20, 2003

**AMENDMENT**

This is in response to the Examiner's Action mailed May 21, 2003.

A petition for three-month extension of time accompanies this  
amendment.

Please amend the above-identified application as follows:

**Amendments to the Claims** are reflected in the listing of claims  
which begins on page 2 of this paper.

**Remarks/Arguments** begin on page 5 of this paper.